

Notice of References Cited

Application/Control No.

10/535,388

Applicant(s)/Patent Under

Reexamination

KUSUNOKI ET AL.

Examiner

Aaron Williams

Art Unit

4135

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-2002/0027411	03-2002	Bae et al.	313/461
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Y.N. Kim et al., "Adhesive and Wear properties of Indium Tin Oxide (ITO) THin Films Deposited by RF MAGnetron Sputter", Key Engineering Materials Vols. 317-318 (2006)
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a))
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